

Elite300™

Advanced accuracy, precision and performance in an ultra-efficient measurement environment

Versatile microscope mounts for every application

- High-stability bridge mount ideal for fine structure probing, using programmable 75 mm (3") X-Y sub-micron transport and 150 mm (6") linear Z lift (motorized and manual transports also available)
- Large-area bridge mount with 300 mm (12") X-Y ideal for array and large-area WLR probing

Universal accessory mounting system

- Use with all IV/CV connection panels, vacuum and positioner mounts
- Multiple locations for coax, triax and dual-triax cables
- Fast reconfigurability for multiple test needs

Patented AttoGuard®

- Makes the station invisible to your IV and CV instruments
- < 1 fA noise in triaxial IV measurements
- 10 aF resolution CV measurements
- Improved settling time with new thermal isolation

Large-area Tophat

- Fast setup in < 1 minute
- 20 % increased working area
- Wide 40 mm RF probe-tip separation
- Optimized for all DC and RF measurement probes

Flexible seals

- Accommodates up to eight low-noise probe positioners
- Ensures light-tight and EMI integrity

Quick access control panel for common tasks

Patented MicroChamber®

- Chuck enclosure ensures moisture-free, light-tight EMI-protected measurements, eliminates dark box, making over-temperature measurements easy

Safety load and unload wafers

- Full wafer access via locking roll out stage

Safety interlocks

- X-Y motion control safety interlock
- IV instrument high-voltage safety interlock

Adjustable platform height for increased user comfort

Small-footprint, fully integrated system

- Built-in components: motion control, computer controller, anti-vibration and air-management systems

Unattended testing over multiple temperatures

- Eliminate the idle time between temperature transitions with VueTrack™ technology
- Minimized thermal drift and reduced die soak with HTS (High-Thermal Stability) enhancements

Next-generation PureLine™ II

- 10x better spectral noise (≤ -170 dBVrms/rtHz)
- 4x better system AC noise (≤ 5 mVp-p)
- Guaranteed shielding effectiveness
- World's best station for low-level and 1/f measurements

Powerful automation tools for data collection

- Automatic wafer alignment
- Auto XYZ and theta correction for sub-micron stepping
- Automatic die size measurement tool

Fast test and measurement software integration

- Real-time wafer mapping
- Point-and-shoot navigation
- IEEE, remote communication support

"Hands-free" microscope remote control

- With programmable and motorized transports

Ergonomic accessory mount for system control

Ergonomic arm rest for easy sub-micron probing

Quick access to auxiliary chucks

- Two patented auxiliary chucks with vacuum controls
- Temperature-stable HF-CV and RF calibration standards
- Easy probe-tip cleaning using cleaning substrates

Manual X-Y stage controls

Automatic MicroChamber air-purge system

- Faster thermal transitions and auto dry air-purge controls for "cold" probing

Patented FemtoGuard® triaxial guarding technology

Wide-temperature probing

- -60 °C to 300 °C systems for characterization & modeling
- 400 °C systems for WLR and power applications
- Stable measurements with thermally optimized platen, MicroChamber and ultra-flat wafer chucks

Next-generation, semi-automatic stage

- Fast linear motor/air bearing technology (200 mm/sec)
- Super high-accuracy, temperature-compensating design
- Precision wafer stepping and high-force Z stage

*Optimal test instrument integration

Instrument shelf available as an option to streamline cabling to the test instruments and to minimize footprint

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